

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (currently amended) Apparatus (1) for treating wafer-shaped articles, comprising:

a linear arranged process unit array of at least two process units (31, 33), wherein in each said process unit only and exactly one single wafer-shaped article (Wm) can be treated at one time;

at least one cassette-holding unit (15), each cassette-holding unit for holding at least one cassette storing at least one wafer-shaped article therein;

a transport system for picking a held wafer-shaped article from the one cassette and placing the thus picked-up wafer-shaped article into one of the process units, the transport system comprising

i) at least one linear track (26) arranged parallel to the process unit array (31, 33), the track for moving the picked-up single wafer-shaped article along a linear path parallel to the process unit array, and

ii) a transport unit (46) movably mounted on each of said at least one linear track (26), said transport unit comprising at least one holding means (46a) for holding the

picked-up wafer-shaped article in a substantially vertical plane parallel to the linear track and moving the picked-up wafer-shaped article along a transport path defined by the linear track, wherein the transport unit (46) has a pivoting (66) mechanism for pivoting (P) the picked-up wafer-shaped article from a substantially vertical state to a substantially horizontal state to place the picked-up wafer-shaped article in one of the process units;

a front unit comprising

i) an array of at least two of the cassette-holding units (15) for holding cassettes storing a plurality of the wafer-shaped articles, and

ii) a transfer unit (84, 86) for transferring the wafer-shaped articles between the cassettes and the transport unit (46); and

at least one transfer station (22) for temporarily storing the picked-up wafer-shaped article (Wt),

the transfer station being accessible by the transfer unit (84, 86) and by the transport unit (46) movably mounted on the linear track,

wherein said transfer station further comprises a holding unit (42) with two holding devices (42a, 42b) arranged in a back-to-back configuration.

2-4. (canceled)

5. (currently amended) Apparatus as claimed in claim [[4]] 1, wherein said transfer station (22) comprises a flip mechanism for flipping (Fv) the picked-up wafer-shaped article.

6-8. (canceled)

9. (previously presented) Apparatus as claimed in claim 1, with a transport system comprising at least two of said at least one linear tracks (24, 26)..

10. (previously presented) Apparatus as claimed in claim 1, wherein,

each process units (31, 33) treats the only exactly one single wafer-shaped article (Wm) in a horizontal position, and a transport path of the held wafer is narrower than a diameter of the held wafer.

11-17. (canceled)